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IFW

In re Patent Application of: Abdurrahman Sezginer et al.

Atty Docket No. TWI-32410

Application No.: 10/613,378

Filed: July 3, 2003

Confirmation No.: 7200

For: OVERLAY METROLOGY METHOD AND APPARATUS USING MORE THAN ONE GRATING PER MEASUREMENT DIRECTION

M/S AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

Sir:

Transmittal herewith is an amendment in the above-identified application.

The fee has been calculated as shown below.

	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL	13	MINUS	20	0	x \$50 =	\$0
INDEP.	3	MINUS	3	0	x \$200 =	\$0
FIRST PRESENTATION OF MULTIPLE DEP CLAIMS					+ \$360	\$0
TOTAL						\$0

Small Entity 50% Filing Fee Reduction (if applicable)

\$0

- \* If the entry in Col. 1 is less than the entry in Col. 2, write "0" in Col. 3  
\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 20, write "20" in this space.  
\*\*\* If the "Highest Number Previously Paid For" IN THIS SPACE is less than 3, write "3" in this space. The "Highest Number Previously Paid For" (Total or Independent) is the highest number found from the equivalent box in Col. 1 of a prior amendment or the number of claims originally filed.)

- ☒ No additional fee is required.
- ☐ A check in the amount of \$\_\_\_\_\_ is attached.
- ☒ Please charge any additional fees, including any fees necessary for extensions of time or credit overpayment to Deposit Account No. 50-1703, under Order No. TWI-32410.  
**A duplicate copy of this sheet is enclosed.**
- ☒ Petition for extension of time. The undersigned attorney of record hereby petitions for an extension of time pursuant to 37 C.F.R. § 1.136(a), as may be required, to file this response.

STALLMAN & POLLOCK LLP

Dated: May 11, 2005

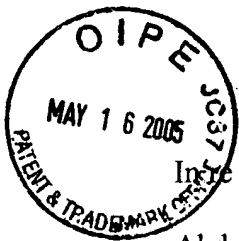
By: Michael A. Stallman  
Michael A. Stallman (Reg. No. 29,444)  
Attorneys for Applicant(s)

**CERTIFICATE OF MAILING**

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on May 12, 2005.

Dated: May 12, 2005

By: Georgia K. Stith  
Georgia K. Stith



## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of  
Abdurrahman Sezginer et al.

Application No.: 10/613,378

Filed: July 3, 2003

For: OVERLAY METROLOGY METHOD AND  
APPARATUS USING MORE THAN ONE  
GRATING PER MEASUREMENT  
DIRECTION

Confirmation No.: 7200

Group Art Unit: 2877

Examiner: Gordon J. Stock, Jr.

**RESPONSE TO RESTRICTION  
AND/OR ELECTION REQUIREMENT  
MAILED APRIL 27, 2005**

353 Sacramento Street, Suite 2200  
San Francisco, CA 94111  
Telephone: (415) 772-4900

M/S AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
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Box 1450, Alexandria, VA 22313-1450 on May 12, 2005.

STALLMAN & POLLOCK LLP

Dated: 05/12/2005

By: Georgia K. Stith

Georgia K. Stith

Sir:

In response to the Restriction and/or Election Requirement mailed April 27, 2005,  
Applicants respond as follows:

In the Office Action, the Examiner issued a Restriction Requirement. More specifically,  
the Examiner indicated that the claims fall within two groups, Group I (claims 1-5) drawn to an  
overlay target, and Group II (claims 6-13) drawn to a method for optically inspecting and  
evaluating a semiconductor wafer.

Applicants hereby elect to prosecute Group I (claims 1-5) without traverse.

Respectfully submitted,

STALLMAN & POLLOCK LLP

Dated: May 11, 2005

By: Michael A. Stallman

Michael A. Stallman (Reg. No. 29,444)

Attorneys for Applicant(s)